

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

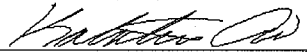
Applicant : Chou San Nelson Loke, et al.
Appl. No. : 10/781,247
Filed : February 18, 2004
For : SYSTEM AND METHOD OF
CVD CHAMBER CLEANING
Examiner : Keath Chen
Group Art Unit : 1709

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November 13, 2007

(Date)


Katsuhiro Arai, Reg. No. 43,315

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed July 13, 2007, please reconsider the present application in light of the following amendments and comments.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.